

**Amendments to the Claims:**

This listing of claims will replace all prior versions, and listings, of claims in the application:

**Listing of Claims:**

1. (Currently Amended) A vacuum processing apparatus comprising a pressure-reduction container, exhaust means joined to said pressure-reduction container, and a processing object introducing door connected to said pressure-reduction container through a door gasket, and a plurality of gaskets for ensuring airtightness of said pressure-reduction container;

wherein one or more gaskets for said processing object introducing door gasket are said door gasket is made of a material with a small emission of organic matter while the gaskets except the door gasket includes a gasket formed by either one of a metal and a ceramic.

2. (Currently Amended) A vacuum processing apparatus according to claim 1, characterized in that the constituent material of said door gasket contains organic matter.

3. (Currently Amended) A vacuum processing apparatus according to claim 2, characterized in that the constituent material of said door gasket has been subjected to a process of contacting it with water at 80°C or more.

4. (Currently Amended) A vacuum processing apparatus according to claim 2, characterized in that a main component of said constituent material containing organic matter is a perfluoroelastomer.

5.-8. (Cancelled)

9. (Previously Presented) A vacuum processing apparatus according to claim 1, characterized in that said exhaust means comprises a pump and causes a small amount of an inert gas to flow upstream of said pump or at a pump purge portion.

10. (Previously Presented) A vacuum processing apparatus according to claim 1, characterized in that said exhaust means comprises a primary pump, a secondary pump connected to an exhaust side of said primary pump, and a gas introducing portion for introducing an inert gas between said primary pump and said secondary pump.

11. (Previously Presented) A vacuum processing apparatus according to claim 1, characterized in that a degree of vacuum at the time of treatment is 100 Torr or less.

12. (Previously Presented) A vacuum processing apparatus according to claim 1, characterized in that said vacuum processing apparatus is a reduced-pressure processing apparatus.

13. (Previously Presented) A vacuum processing apparatus according to claim 1, characterized in that said vacuum processing apparatus is a vapor deposition apparatus.

14. (Currently Amended) A vapor deposition apparatus ~~comprising a pressure reduction container, exhaust means connected to said pressure reduction container, a substrate introducing door connected to said pressure reduction container, a plurality of gaskets for ensuring airtightness of said pressure reduction container, and a deposition source container, said vapor deposition apparatus characterized in that a constituent material of the gasket, in said plurality of gaskets, for ensuring airtightness of a portion with low attach/detach frequency is at least one of a metal and a ceramic according to claim 1, further comprising a deposition source container.~~

15.-18. (Cancelled)

19. (Currently Amended) A vapor deposition apparatus according to claim [[18]] 14, characterized in that an inner surface of said deposition source container contains at least one of an oxide or a nitride of an element selected from Si, Cr, Al, La, Y, Ta, Ti, and B, or C.

20. (Cancelled)

21. (Currently Amended) A vapor deposition apparatus according to claim [[20]] 14, characterized in that ~~said high thermal conductivity material forming~~ said deposition source container contains at least one of a nitride of Al, B, or Si, C or a metal material.

22.-23. (Cancelled)

24. (Previously Presented) A vapor deposition apparatus according to claim 14, characterized in that a deposition material put into said deposition source container is an organic EL element material.

25.-27 (Cancelled)

28. (Currently Amended) An organic EL element characterized by comprising an organic layer formed by the use of the vapor deposition apparatus according to claim [[14]] 1.

29. (Currently Amended) An organic EL display device characterized by comprising an organic layer formed by the use of the vapor deposition apparatus according to claim [[14]] 1.

30. (Currently Amended) A vacuum processing apparatus comprising a plurality of airtight sealing members, ~~said vacuum processing apparatus characterized in that at least one of said plurality of airtight sealing members has been applied with an organic matter emission prevention process which are different from each other in frequencies of attach/detach and which are classified into a first sealing member of a high frequency of the attach/detach and a second sealing member of a low frequency of the attach/detach, wherein the first sealing member is formed by an organic matter subjected to an emission prevention process while the second sealing member is formed by a matter different from the organic matter.~~

31. (Cancelled)

32. (Currently Amended) A vacuum processing apparatus ~~comprising a plurality of airtight sealing members employed at portions that are detachably used, said vacuum processing apparatus characterized in that, in said plurality of airtight sealing members, the airtight sealing member at the portion with high attach/detach frequency and the airtight sealing member at the portion with low attach/detach frequency are made of mutually different materials and said airtight sealing member at said portion with the high attach/detach frequency is made of the material containing according to claim 30, wherein the organic matter of the first sealing member contains a perfluoroelastomer as a main component.~~